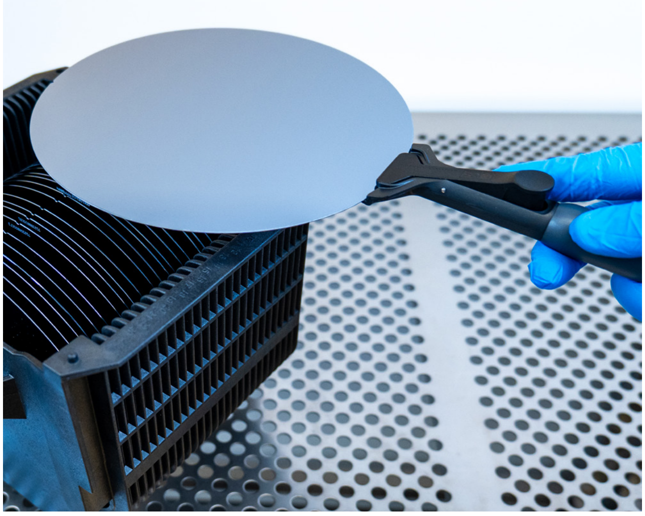
MANUAL MECHANICAL WAFER EDGE GRIPPER

The WHS-G1 series is a precision-engineered manual wafer edge gripper designed for safe, efficient handling of wafers with thicknesses ranging from 120 µm to 1000 µm.



This antistatic, normally-closed mechanical tool is ideal for applications where traditional backside contact methods are not suitable, such as bonded wafers, double topography, Taiko, TSV, MEMS, and optical wafers. The bottom gripper material is ESD-safe PEEK, offering longevity, antistatic protection, and chemical resistance in demanding cleanroom environments. Featuring a 3 mm perfluorocarbon elastomer front side touch pad, the WHS-G1 ensures secure wafer handling without risking scratches or contamination. Its ergonomic, weighted handle and easy-to-use trigger provide precise control and reduce operator fatigue during long periods of manual wafer handling. The design is optimized for SEMI Standard round substrates, making it versatile for both silicon and compound wafers.

The WHS-G1 is not only suitable for standard wafer handling tasks like manual transferring, sorting, and loading, but also excels in more specialized operations, such as rescuing wafers stuck inside process tools or automation systems. It can also be used for inspecting wafers for macro defects, particles, and scratches, with its edge-only handling method reducing the risk of contamination.

This gripper is a cost-effective alternative to vacuum wands and tweezers, providing superior handling without leaving scratches or debris. Manufactured in an ISO9001 and CE certified facility, the WHS-G1 meets international standards for safety and performance, offering a reliable solution for high-precision wafer handling in cleanroom environments.

FEATURES AND ADVANTAGES

- Normally-closed edge gripper for secure wafer handling
- Ergonomic design with easy-to-use trigger for operator comfort
- ISO 4 (Class 10) cleanroom compatible
- 3 mm perfluorocarbon elastomer touchpad for scratch-free wafer contact
- ESD-safe construction for durability and chemical resistance

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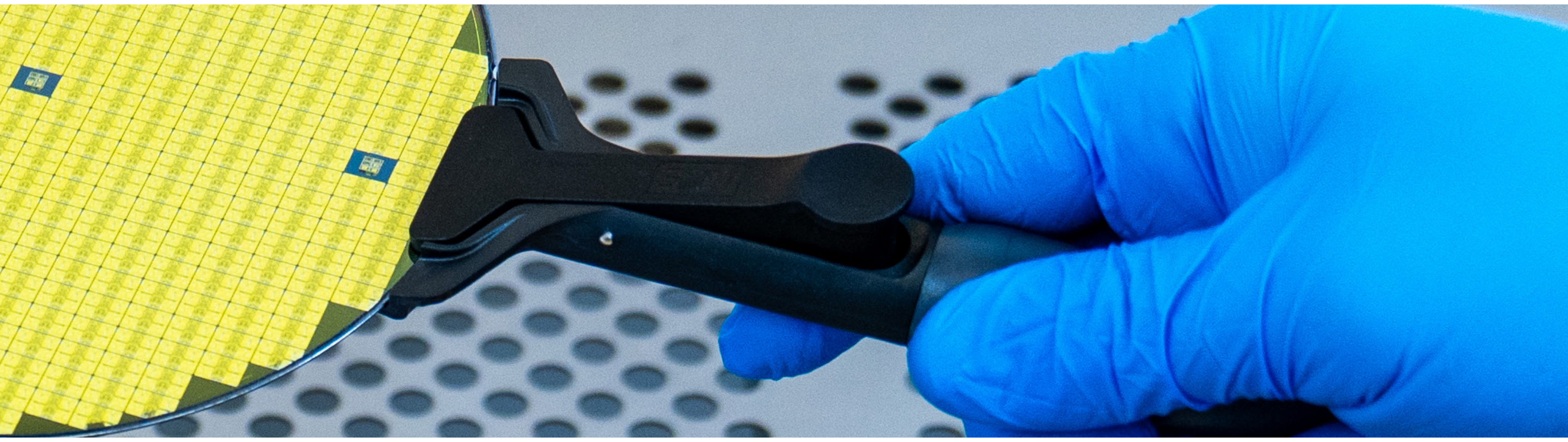
MANUAL MECHANICAL WAFER EDGE GRIPPER

ITEM	SPECIFICATIONS
Wafer sizes	50-76, 100-125, 150, 200 mm
Material, bottom grip	Antistatic PEEK
Material, top grip	Perfluorocarbon elastomer
Grip hold	Normally closed
Cleanliness	ISO 4 (Class 10 FS209E)



ORDERING INFORMATION

WHS-G1 - 23

CODE	MODEL
23	Mechanical wafer pick, 50-76 mm wafer
45	Mechanical wafer pick, 100-125 mm wafer
6	Mechanical wafer pick, 150 mm wafer
8	Mechanical wafer pick, 200 mm wafer

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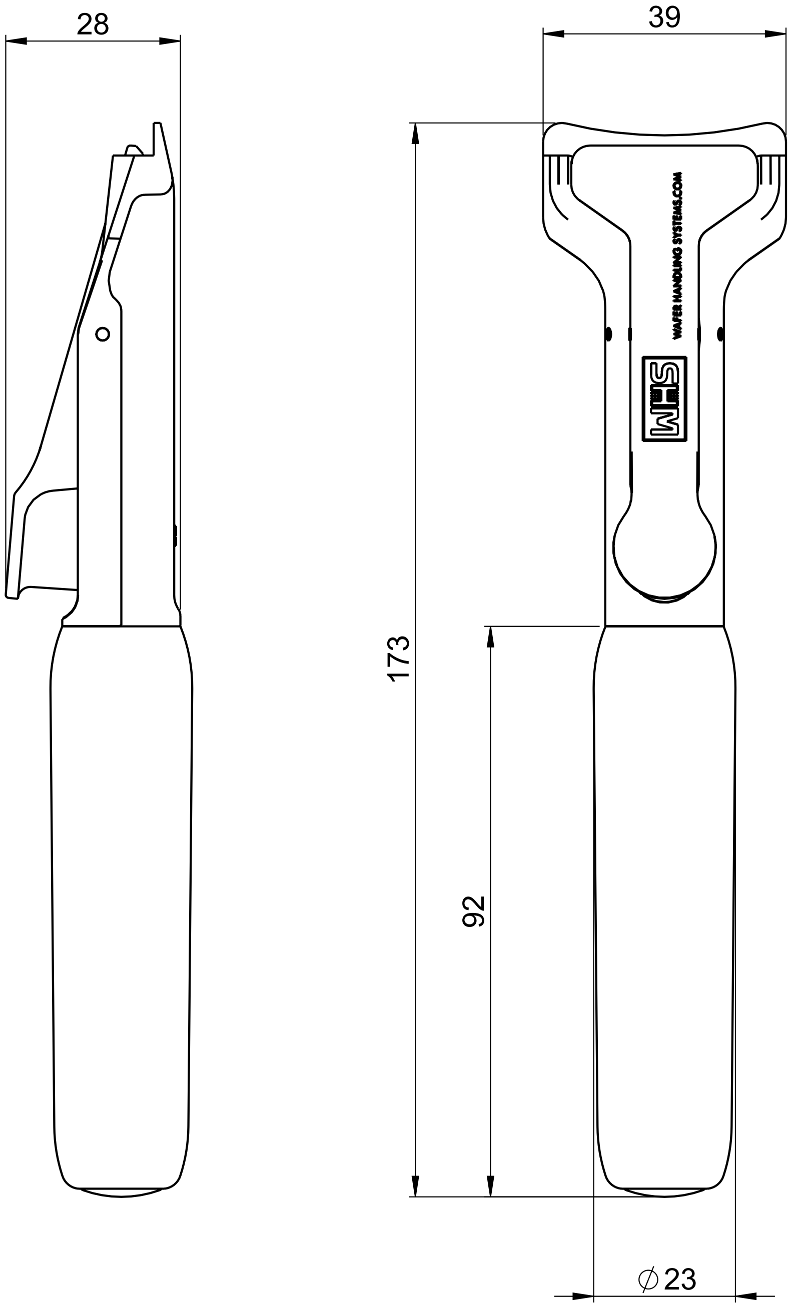

Materials:
Handle: Antistatic Polycarbonate
Trigger: Polyamide
Body/Gripper: Antistatic PEEK
Wafer Touchstrip: Perfluoro Elastomer

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WHS-G1-23

Mechanical gripper assy, 50-76mm wafer

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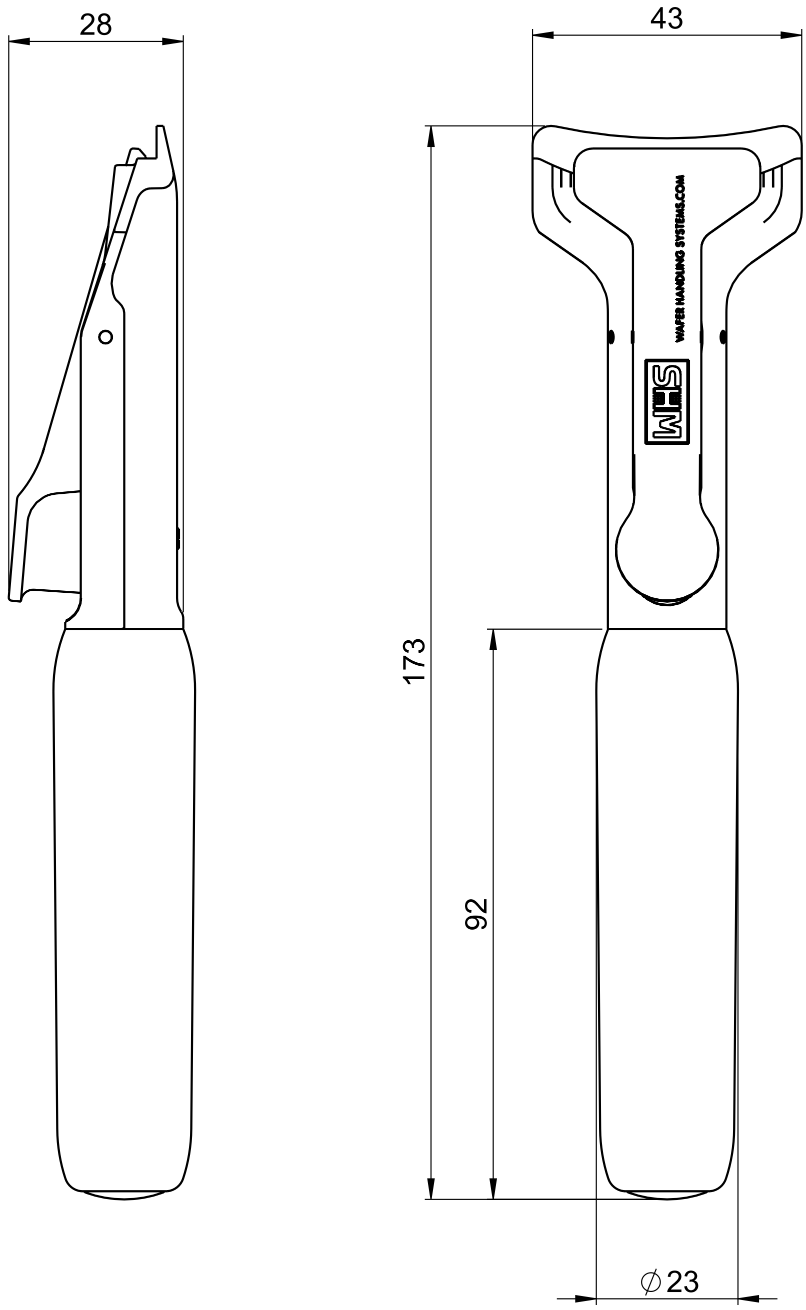

Materials:
Handle: Antistatic Polycarbonate
Trigger: Polyamide
Body/Gripper: Antistatic PEEK
Wafer Touchstrip: Perfluoro Elastomer

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WHS-G1-45

Mechanical gripper assy, 100-125mm wafer

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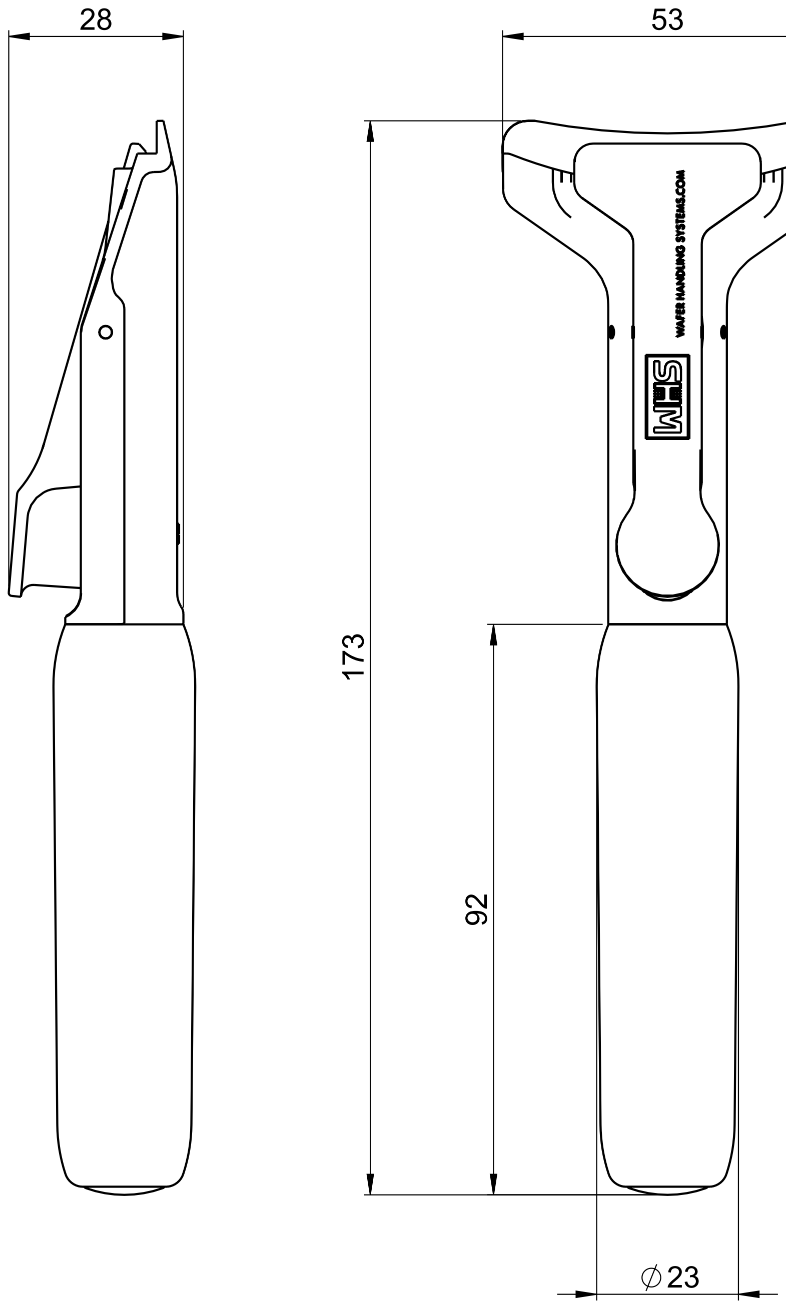

Materials:
Handle: Antistatic Polycarbonate
Trigger: Polyamide
Body/Gripper: Antistatic PEEK
Wafer Touchstrip: Perfluoro Elastomer

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WHS-G1-6

Mechanical gripper assy, 150mm wafer

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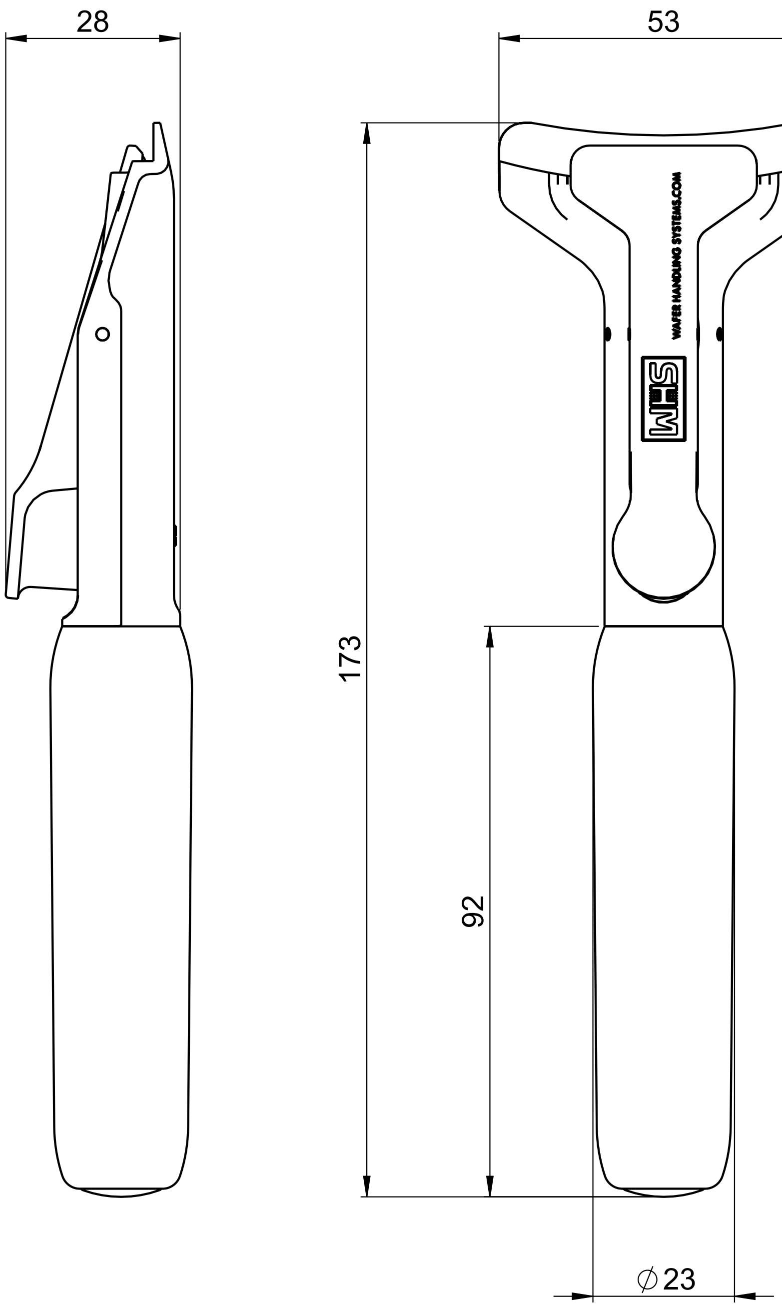

Materials:
Handle: Antistatic Polycarbonate
Trigger: Polyamide
Body/Gripper: Antistatic PEEK
Wafer Touchstrip: Perfluoro Elastomer

WAFER HANDLING SYSTEMS.COM

WHS-G1-8

Mechanical gripper assy, 200mm wafer

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